

**IN THE
UNITED STATES PATENT & TRADEMARK OFFICE**

Applicant: YU CHENG et al.

Examiner: Everhardt, Caridad

Application No. 10/738,360

Group No. 2825

Filed: December 16, 2003

Confirmation No. 8563

Title: METHODS AND APPARATUS FOR
THE OPTIMIZATION OF PHOTO RESIST
ETCHING IN A PLASMA PROCESSING
SYSTEM

CERTIFICATE OF FACSIMILE TRANSMISSION
I hereby certify that this correspondence is being faxed to the USPTO
at 703-872-9306 on January 27, 2005.
9 PAGES TOTAL (inclusive).

Signed: /Hanh H. Bui/
Hanh H. Bui

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JAN 27 2005

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Amendment A Transmittal

Transmitted herewith is an Amendment in the above-identified application in response to the Office Action mailed July 27, 2004.

The fee has been calculated as shown below.

	Claims Remaining After Amendment	Highest Previously Paid For	Present Extra	SMALL ENTITY RATE FEE		LARGE ENTITY RATE FEE
TOTAL CLAIMS	<u>24</u> -	<u>24</u>	<u>0</u>	X 9 = \$	OR	X18 = \$ 0
INDEP CLAIMS	<u>3</u> -	<u>2</u>	<u>0</u>	X44 = \$	OR	X88 = \$ 0
[] Multiple Dependent Claim Present and Fee Not Previously Paid				\$130=\$0		\$260= \$ 0
TOTAL						\$ 0

- ☒ An extension of 3 months is requested.
☒ An amendment totaling 3 pages is enclosed herewith.
☐ Formal drawings totaling pages is enclosed herewith.
☒ A credit card payment of \$1020 is enclosed herewith.
☒ Please consider this communication a petition for any necessary petition and charge any additional fees required to facilitate filing the enclosed response, to Deposit Account No. 50-2284 (Order No. LMRX-P029).

Respectfully submitted,
/Joseph A. Nguyen/
Joseph A. Nguyen, Esq. (Reg. No. 37,899)

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Attorney Docket No. LMRX-P029/P1180

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Application No. 10/738,360

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PATENT APPLICATION
ATTORNEY DOCKET NO. LMRX-P029/P1180

IN THE
UNITED STATES PATENT & TRADEMARK OFFICE

In re application of: Yu Cheng et al. Serial No.: 10/738,360 Filed: December 16, 2003 Title: METHODS AND APPARATUS FOR THE OPTIMIZATION OF PHOTO RESIST ETCHING IN A PLASMA PROCESSING SYSTEM	Group Art Unit: 2825 Examiner: Everhart, Caridad Docket: LMRX-P029/P1180
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AMENDMENT A

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed July 27, 2004, please amend the above-identified application as follows:

Amendments to the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.